Maple II I Micro Raman / PL



Key Features

- High Performance Raman PL / PLE / EL
- Compatible with Various Detectors
- High Resolved PL Mapping

Application

- Semiconductor Characterization and Testing (III-V Materials)
- GaN / ZnO LED Wafer Surface Characterization (Surface Containment, Uniformity, Reflectivity, Thickness and Bowing Test)
- Solar Cell EL Measurement
- Sensor Development for NIR Range

- Gemstone PL, Diamond by HPTP
- Development of Material of LED with GaN / GaAs
- Diamond Anvil PL
- TDIPL & IQE

Specification

Wavelength	266 / 325 / 532 / 632.8 / 785 / 1064 nm (Up to 6 Different Laser)	Wavelength	High Performance Spectroscopic Micro Sample Chamber
Beam Quality	<1.2 M^2	PC Control	Sample Stage & Filter Wheel
Output Power	18 / 50 / 90 / 100 / 200 mW (CW mode)		
	320 mm / 500 mm (Two Exit Port)	Detector Type	TE Cooled CCD (Open Electrode)
Focal Length	· · · /	Туре	
Focal Length	320 mm / 500 mm (Two Exit Port) 0.09 nm		TE Cooled CCD (Open Electrode) 1024 * 256
Focal Length Spectral Resolution Stray Light Rejection	· · · /	Туре	
Spectral Resolution	0.09 nm	Type Pixel Format	1024 * 256

Maple II System

I Micro Raman / PL



Key Features

- Turn-key System From Laser to Microscope
- Fully Compatible with Various Peripheral Devices
- DXG's Own Mapping Solution Adopted

System Configuration

Input Laser Source		Spectrograph	
325 nm He-Cd Laser set	50 mW @ 325 nm	Focal Length	320 mm, 500 mm (Two Exit Port)
Output Power	25 mW @ 325 nm		200 ~ 1000 nm (UV-VIS)
532 nm Solid State Laser set Output Power	200 mW @ 532 nm	Wavelength Range	900 ~ 1700 nm (NIR)
		Develoption	0.05 nm or 0.1 nm @ 435.8 nm 1200 gr/mm Grating
785 nm Stabilized Laser set	00 111 0705	Resolution	10 um Slits <2 cm - 1 @ 785 nm 2400 gr/mm
Output Power	90 mW @785 nm		

CCD D

Sample Chamber	Sam	ıþle	Cham	ber
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	75 * 50 mm	
Large Area X-Y Stepper Motorized Stage	Travel Range (Typical) up to 200 * 200 mm (Optional)	
	0.05 um Minimum Resolution	
Power Control	PC Controlled ND Filter Wheel (Optical Density : 0 ~ 3)	
Motorized Filter Wheel System	Automatically Change Depend on Input Laser Source	
Beam Spot Size	<1 um @ Fulfilled Entrance Aperture & Gaussian Beam Profile, 532 nm	
Ohio the Long	50 x / N.A.0.55, W.D.13 mm FL : 4 mm For 400 - 1100 nm	
Objective Lens	40x LMU-NUV/N.A.0.5, W.D.1 mm For 325 - 750 nm	

Options	
Calibration	Semi-auto Calibration
Functions	Select Monochromator, Serial Port , Turret, Grating & Current Wavelength Information, Wavelength Range, Number of Point / Resolution, Integrating Time, Accumulation
Features	Easy Parameter Selection
Software	
	200 ~ 1000 nm Detecting Range (95 % @ 800 nm
CCD Detector	26 * 26 um Pixel Size
	1024 * 256 Pixel CCD